

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: S. KADLEC, et al.  
Serial No: 10/798,331  
Filed: March 12, 2004  
Title: METHOD FOR MANUFACTURING SPUTTER-COATED  
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING  
CHAMBER WITH SUCH SOURCE  
Group: 1753  
Examiner: Michael A. Band  
Conf. No.: 6134

**LETTER**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 4, 2008

Sir:

This Letter is responsive to the Interview Summary mailed in the above-identified application on December 12, 2007 and summarizing the results of the December 6, 2007 telephone interview granted by Examiner Michael Band and applicants undersigned attorney. The stated summary of the interview is correct. A more detailed statement of the substance of interview as required by M.P.E.P. §713.04 is set forth in the remarks in the Amendment filed in the application on December 6, 2007.

Respectfully submitted,

/Ronald J. Shore/  
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RJS/kmh